

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. *(Currently Amended)*: A lithographic support system, comprising:  
a moveable support structure configured to support and move an object, said support structure comprising a robot arm having a rod coupled to a support frame that is provided with a clamp that clamps the object; and  
a flexible compliant structure configured to ~~compensate for at least one of a tilt and displacement~~ absorb a force created by a collision between said object and said clamp, the flexible compliant structure being provided at least between the rod and the support frame.
2. *(Cancelled)*
3. *(Currently Amended)*: The lithographic support system of Claim 1, wherein said flexible compliant structure comprises two or more compliant rods that are rotatable at their ends.
4. *(Currently Amended)*: The lithographic support system of Claim 1, wherein said flexible compliant structure comprises a notch such that a front portion of the support frame is enabled to rotate.
5. *(Currently Amended)*: The lithographic support system of Claim 1, further comprising a second flexible compliant structure provided on said clamp.
6. *(Currently Amended)*: The lithographic support system of Claim 1, wherein said support frame is in a plane defined by a x-axis, a y-axis, and a z-axis being perpendicular to said x-axis and said y-axis, said flexible compliant structure providing a compliance in at least one of a first rotation (~~R<sub>x</sub>~~) about said x-axis, a second rotation (~~R<sub>y</sub>~~) about said y-axis, and a z-direction parallel to said z-axis.

7. *(Currently Amended)*: The lithographic support system of Claim 3 1, wherein said flexible compliant structure is arranged such that said support frame is allowed to rotate about a predetermined center of rotation.

8. *(Currently Amended)*: The lithographic support system of Claim 1, wherein said object comprises a substrate (~~W~~).

9. *(Cancelled)*

10. *(Currently Amended)*: The lithographic support system of Claim 1, wherein said flexible compliant structure comprises a metal flexure.

11.-14. *(Cancelled)*

15. *(Currently Amended)* A lithographic robot, comprising:  
a robotic arm configured to hold and move an object, the robotic arm having a rod coupled to a support frame that is provided with a clamp; and  
a flexible compliant structure configured to ~~compensate for at least one of a tilt and displacement~~ absorb a force created by a collision between said object and said robotic arm, the flexible compliant structure being provided at least between the rod and the support frame.

16. *(Currently Amended)*: The lithographic robot of Claim 15, wherein said flexible compliant structure comprises two or more flexible compliant rods that are rotatable at their ends.

17. *(Currently Amended)*: The lithographic robot of Claim 16, wherein said flexible compliant structure comprises a notch such that a front portion of the support frame is enabled to rotate.

18. *(Currently Amended)*: A lithographic apparatus, comprising:  
a radiation system configured to provide a beam of radiation;  
a support structure configured to support a patterning device that imparts a desired pattern onto said beam of radiation;

a substrate holder configured to hold a substrate;  
a projection system configured to project said patterned beam onto a target portion of said substrate; and  
a support system that holds and moves one of said substrate, said patterning device, and an object, in which said support system comprises:  
a support frame provided with a clamp;  
a rod coupled to the support frame; and  
a flexible compliant structure configured to ~~compensate for at least one of~~  
~~a tilt and displacement~~ absorb a force created by a collision between said substrate, said patterning device, or said object and said clamp, the flexible compliant structure being provided at least between the rod and the support frame.

19.-20. *(Cancelled)*

21. *(Currently Amended)*: A device manufacturing method, comprising:  
providing a substrate via a support system, said supporting system comprising a rod coupled to a support frame that is provided with a clamp structure that clamps said substrate, said supporting system configured to hold and move said substrate and ~~compensate for at least one of a tilt and displacement~~ absorb a force created by a collision between said substrate and said clamping structure by employing a flexible compliant structure provided at least between the rod and the support frame;  
providing a beam of radiation using a radiation system;  
imparting a desired pattern onto said beam of radiation by a patterning device; and  
projecting said patterned beam of radiation onto a target portion of said substrate via a projection system.

22. *(Cancelled)*

23. *(Previously Presented)* The lithographic support system of Claim 1, wherein the clamp is in contact with the object.

24. *(Currently Amended)* The lithographic support system of Claim 1, wherein the flexible compliant structure is arranged at least between the rod and the support frame so as to be in a contactless relationship with the object.

25. *(Currently Amended)* The lithographic support system of Claim 1, wherein the flexible compliant structure is configured to ~~compensate for at least one of a tilt and displacement~~ absorb a force created by a collision between the object and the clamp during transport of the object between a first and a second support, the first and the second support configured to support the object.

26. *(Currently Amended)* A lithographic support system, comprising:  
a moveable support structure configured to support and move an object, the support structure comprising a robot arm having a rod coupled to a support frame that includes a clamp configured to clamp the object; and  
a flexible compliant structure configured to ~~compensate for at least one of a tilt and displacement~~ absorb a force created by a collision between the object and the clamp during transport of the object between a first and a second support, the first and the second support configured to support the object, the flexible compliant structure provided on the rod or the support frame so as to be in a contactless relationship with the object.

27. *(Previously Presented)* The lithographic support system of Claim 26, wherein the clamp is in contact with the object.

28. *(New)* The lithographic support system of Claim 1, wherein the flexible compliant structure includes a flexible material.

29. *(New)* The lithographic robot of Claim 15, wherein the flexible compliant structure includes a flexible material.

30. *(New)* The lithographic apparatus of Claim 18, wherein the flexible compliant structure includes a flexible material.

31. *(New)* The device manufacturing method of Claim 21, wherein the flexible compliant structure includes a flexible material.

32. *(New)* The lithographic support system of Claim 26, wherein the flexible compliant structure includes a flexible material.

33. (New) The lithographic support system of Claim 1, wherein the flexible compliant structure includes at least one pair of leaf springs configured to provide a compliance in at least three degrees of freedom.

34. (New) A lithographic support system comprising:  
a moveable supporting structure configured to move and support an object, the moveable supporting structure including a rod having a clamp mounted on one end of the rod and a compliant portion, the compliant portion provided by at least two notches in the cross section of the rod, the compliant portion providing compliance in one degree of freedom.